

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	Gerhard Karl Strauch
Serial No. 10/	Filing Date: November 26, 2003
Title of Application:	Arrangement Comprising a Support Body and a Substrate Holder which is Driven in Rotation and Gas-Supported Thereon

Mail Stop Non-Fee Amendment
 Commissioner for Patents
 Post Office Box 1450
 Alexandria, VA 22313-1450

Preliminary Amendment

Applicant herewith presents its amendment and remarks. Please amend the claims as detailed below.

In the Claims

1. (currently amended) Arrangement comprising a support body (1) and a substrate holder (2) which is supported thereon and driven in rotation, the gas bearing and the rotary drive being formed by means of gas flowing into the separating gap (7) between support body (1) and substrate (2) from nozzles (11, 12), characterized in that the support body (1) and the substrate holder (2) are formed as rings.
2. Arrangement according to Claim 1 or in particular according thereto, characterized in that the rings rest on top of one another in a self-centering fashion.
3. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that one of the rings (1) includes a ring bead which projects into a ring recess in the other ring (2).
4. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that the substrate is supported on the ring (2) which is driven in rotation only by means of its edge.

5. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that the substrate rests on the ring (2) with minimal contact, preferably only on the tips of needle-like protuberances (13).

6. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that the nozzles (11, 12) open out into grooves, in particular arcuate grooves (10, 12).

7. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that arcuate grooves with gas streams flowing in opposite directions inside them alternate.

8. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized by oppositely directed driving gas streams for rotationally bearing and rotationally driving the rotating ring (1).

9. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that the substrate (3) can be radiation-heated from below through the rings (1, 2).

10. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 1 or in particular according thereto, characterized in that the support body (1) and/or the substrate holder consist of quartz or ceramic material.

11. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 10 or in particular according thereto, characterized in that the rotationally driven ring (2) has a low heat absorption.

12. (currently amended) Arrangement according to ~~one or more of the preceding claims~~ Claim 11 or in particular according thereto, characterized in that the arrangement is part of a device for the heat treatment of semiconductor wafers.

13. (currently amended) Device for the in particular rapid heat treatment of in particular flat objects, such as semiconductors, glass or metal substrates, having a support body (1) and a substrate holder (2) which is supported thereby in such a manner that it can be driven in rotation and on which the flat object (3) can be placed, it being possible to produce a gas cushion beneath the substrate holder by means of gas which emerges from nozzles which open out into a separating gap (7) between support body (1) and holding body (2), on which gas cushion the substrate holder (2) rests in such a manner that it is driven in rotation by directed gas streams, characterized in that the support body (1) and the substrate holder (2) are formed as rings and the device is formed in particular according to ~~one or more of the preceding claims~~ Claim 12.